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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

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Application Number

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First Named Inventor

IZUO

Group Art Unit

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U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER - NON PATENT LITERATURE DOCUMENTS

OTHER - NON PATENT LITERATURE DOCUMENTS			Translation	
Examiner Initials	Doc. No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number (s), publisher, city and/or country where published.	Yes	No**
DN	A 11	H.W. LAU et al.; "High aspect ratio silicon pillars fabricated by electrochemical etching and oxidation of macroporous silicon", <u>Elsevier Science S.A.</u> , pp. 29-31 (1996). (No month)		
DN	A 12	LEHMANN, V.; "The Physics of Macropore Formation in Low Doped n-Type Silicon", <u>J. Electrochem. Soc.</u> , Vol. 140, No. 10, pp. 2836-2843 (Oct. 1993).		
DN	A 13	LEHMANN, V. et al.; "Formation Mechanism and Properties of Electrochemically Etched Trenches in n-type Silicon", <u>J. Electrochem. Soc.</u> , Vol. 137, No. 2, pp. 653-659 (Feb. 1990).		

Examiner Signature

Ronald R. Valentin

Date Considered

6-03

- * A concise statement of relevance is being submitted in lieu of a translation. 37 CFR 1.98(a)(3).
- + An English-language equivalent/patent, or an English-language abstract, or an English-language version of the search report or action by a foreign patent office in a counterpart foreign application indicating the degree of relevance found by the foreign office is being submitted in lieu of a concise explanation of relevance under 37 CFR 1.98(a)(3).